

ABSTRACT

A wastewater treatment system 20 including carbon
dioxide gas injection means 3 for injecting a carbon
5 dioxide gas into wastewater which takes place during
silicon processing to obtain raw wastewater to be treated;
a wastewater tank 2; a filter membrane 11 through which the
raw wastewater is filtered; a liquid forwarding pump 9
which forwards the raw wastewater to the filter membrane
10 11; and circulation/forwarding control means 30 which can
forward concentrated water and/or filtered water to the
wastewater tank 2 and which can regulate the pH of the raw
wastewater to 4.0 to 6.5 to forward this wastewater to the
filter membrane 11, when the amount of the raw wastewater
15 present in the wastewater tank 2 is below a reference
amount.